

ABSTRACT

A bistable MEMS microswitch produced on a substrate and capable of electrically connecting ends of at least two conductive tracks, including a beam suspended above the surface of the substrate. The beam is embedded at its two ends and is subjected to compressive stress when it is in the non-deformed position. The beam has an electrical contact configured to produce a lateral connection with the ends of the two conductive tracks when the beam is deformed in a horizontal direction with respect to the surface of the substrate. Actuators enable the beam to be placed in a first deformed position, corresponding to a first stable state, or in a second deformed position, corresponding to a second stable state, and the electrical contact ensures connection of the ends of the two conductive tracks.